

Nak-kwan Chung

List of Publications by Year in descending order

Source: <https://exaly.com/author-pdf/6992844/publications.pdf>

Version: 2024-02-01

12
papers

88
citations

1684188
5
h-index

1474206
9
g-index

12
all docs

12
docs citations

12
times ranked

110
citing authors

#	ARTICLE	IF	CITATIONS
1	Relationships between properties and rapid gas decompression (RGD) resistance of various filled nitrile butadiene rubber vulcanizates under high-pressure hydrogen. <i>Materials Today Communications</i> , 2022, 30, 103038.	1.9	8
2	Characterization technique of gases permeation properties in polymers: H ₂ , He, N ₂ and Ar gas. <i>Scientific Reports</i> , 2022, 12, 3328.	3.3	3
3	Effect of the High-Pressure Hydrogen Gas Exposure in the Silica-Filled EPDM Sealing Composites with Different Silica Content. <i>Polymers</i> , 2022, 14, 1151.	4.5	11
4	Characterizing the Diffusion Property of Hydrogen Sorption and Desorption Processes in Several Spherical-Shaped Polymers. <i>Polymers</i> , 2022, 14, 1468.	4.5	0
5	Investigation of Physical and Mechanical Characteristics of Rubber Materials Exposed to High-Pressure Hydrogen. <i>Polymers</i> , 2022, 14, 2233.	4.5	6
6	Temperature-Dependence Study on the Hydrogen Transport Properties of Polymers Used for Hydrogen Infrastructure. <i>Applied Science and Convergence Technology</i> , 2021, 30, 163-166.	0.9	2
7	Long-term thermal stability of NPB molecule under high-vacuum. <i>Organic Electronics</i> , 2020, 77, 105446.	2.6	3
8	Structural, Optical and Electrical Properties of HfO ₂ Thin Films Deposited at Low-Temperature Using Plasma-Enhanced Atomic Layer Deposition. <i>Materials</i> , 2020, 13, 2008.	2.9	36
9	Selective Deposition of Al ₂ O ₃ on the Upper Side-Photoelectrode to Improve Dye-Sensitized Solar Cell Efficiency. <i>Journal of Nanoscience and Nanotechnology</i> , 2020, 20, 442-446.	0.9	2
10	Measurement of the Hydrogen Permeability of Various Polymers for High Pressure Hydrogen Storage Vessels and Valves. , 2020, , .		1
11	Degradation Test for an Anodic Aluminum Oxide Film in Plasma Etching. <i>Journal of the Korean Physical Society</i> , 2019, 74, 1046-1051.	0.7	1
12	Effect of Growth Temperature on the Structural and Electrical Properties of ZrO ₂ Films Fabricated by Atomic Layer Deposition Using a CpZr[N(CH ₃) ₂] ₃ /C ₇ H ₈ Cocktail Precursor. <i>Materials</i> , 2018, 11, 386.	2.9	15